



Attorney Docket No. 033082 M 275

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants : Kazuhide HASEBE, et al. **Confirmation No.: 6774**  
U.S. Serial No. : 10/552,262  
Filed : October 5, 2005  
Examiner : Lan Vinh  
Group Art Unit : 1792  
For : SILICON DIOXIDE FILM REMOVING METHOD AND  
PROCESSING SYSTEM

**AFTER FINAL AMENDMENT UNDER 37 C.F.R. § 1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**MAIL STOP: AF**

Sir:

In response the Final Office Action mailed on April 25, 2008, for which the time for response is set to expire July 25, 2008, please amend the above-identified application as set forth below and consider the following remarks.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.